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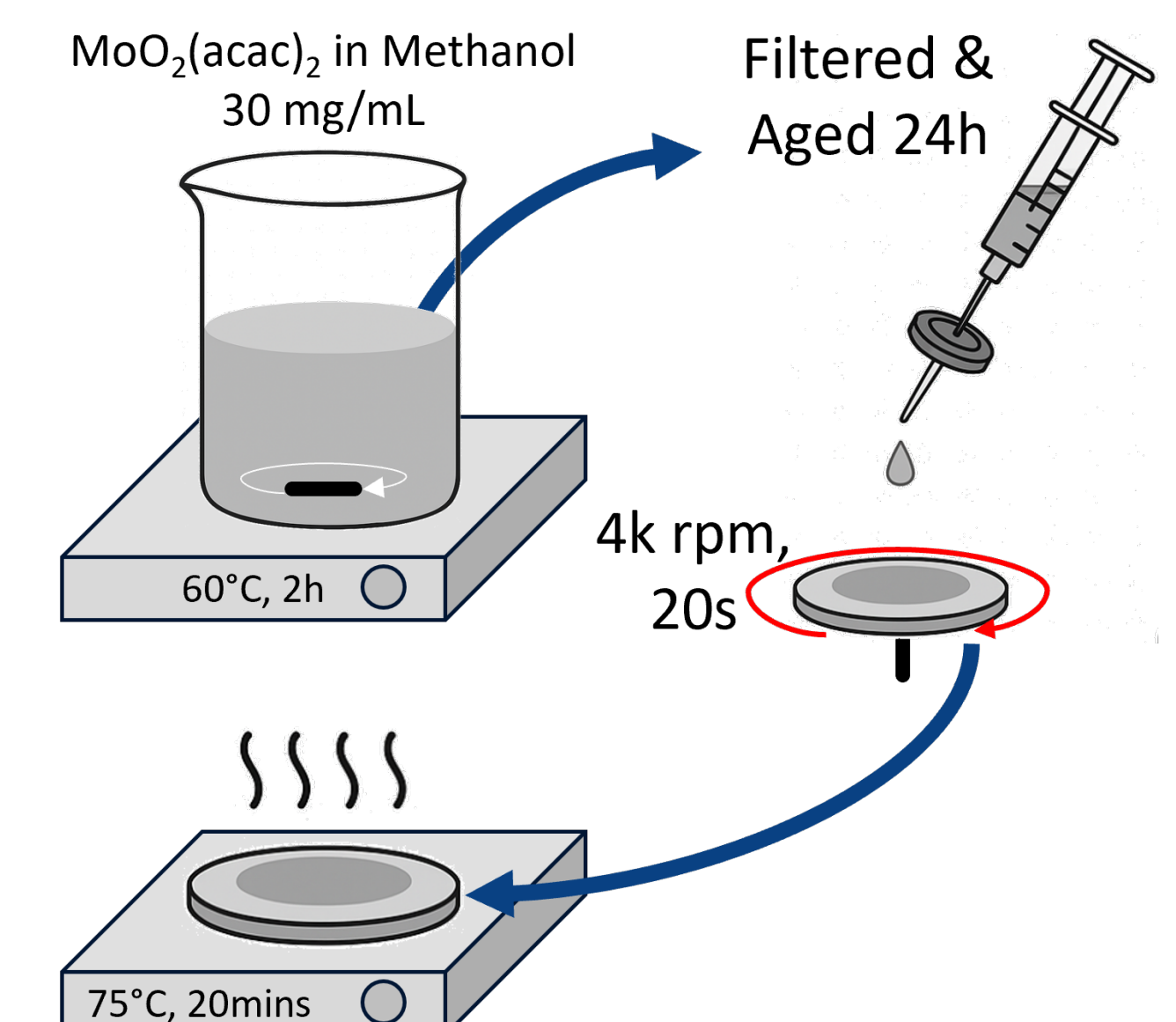
Solution Processed MoO_x Thin Films as Hole Selective Contacts for Silicon Solar Cells

Yida Pan¹, Aga Ridhova¹, Owen Kendall², Jesus Ibarra Michel¹, Di Yan¹, Sergey Rubanov³, Enrico Della Gaspera², James Bullock¹

¹Department of Electrical and Electronic Engineering, University of Melbourne, Parkville, VIC, 3052, Australia
²School of Science, RMIT University, 124 La Trobe Street, Melbourne, Victoria, 3000 Australia
³Ian Holmes Imaging Centre, Bio21, University of Melbourne, Parkville, 3052, VIC, Australia

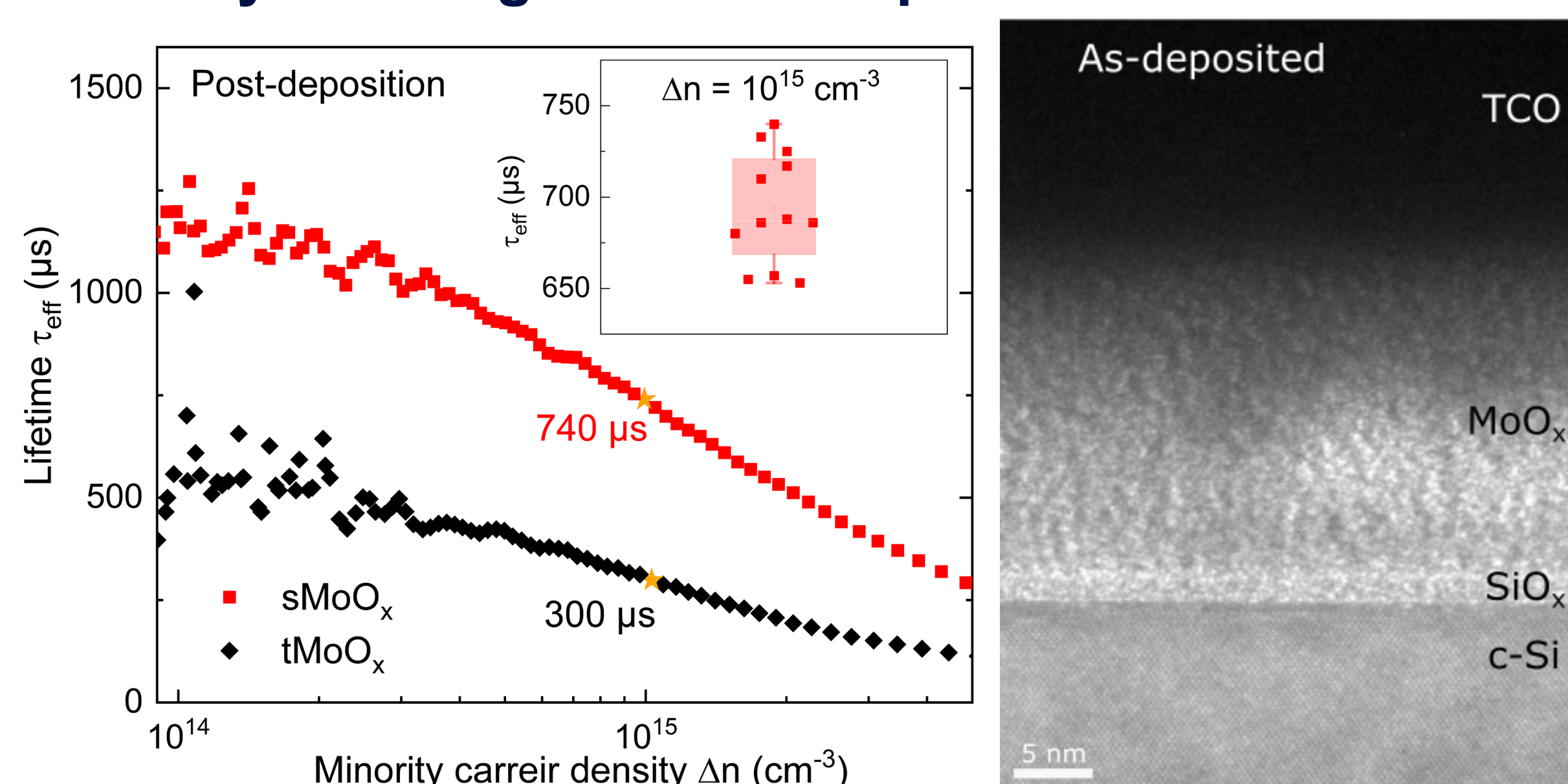
Abstract

Molybdenum oxide (MoO_x) is a promising hole-selective contact for silicon solar cells, but thermally evaporated tMoO_x suffers from poor thermal stability. This work examines solution-processed sMoO_x with various capping layers, showing improved passivation and markedly better thermal stability. Carrier lifetimes up to 740 μs are achieved, and $> 400 \mu\text{s}$ is maintained to 300°C with an indium-oxide capping layer. Although contact resistivity ($\sim 0.3 \Omega\cdot\text{cm}^2$) is higher, it remains suitable for full-area contacts.



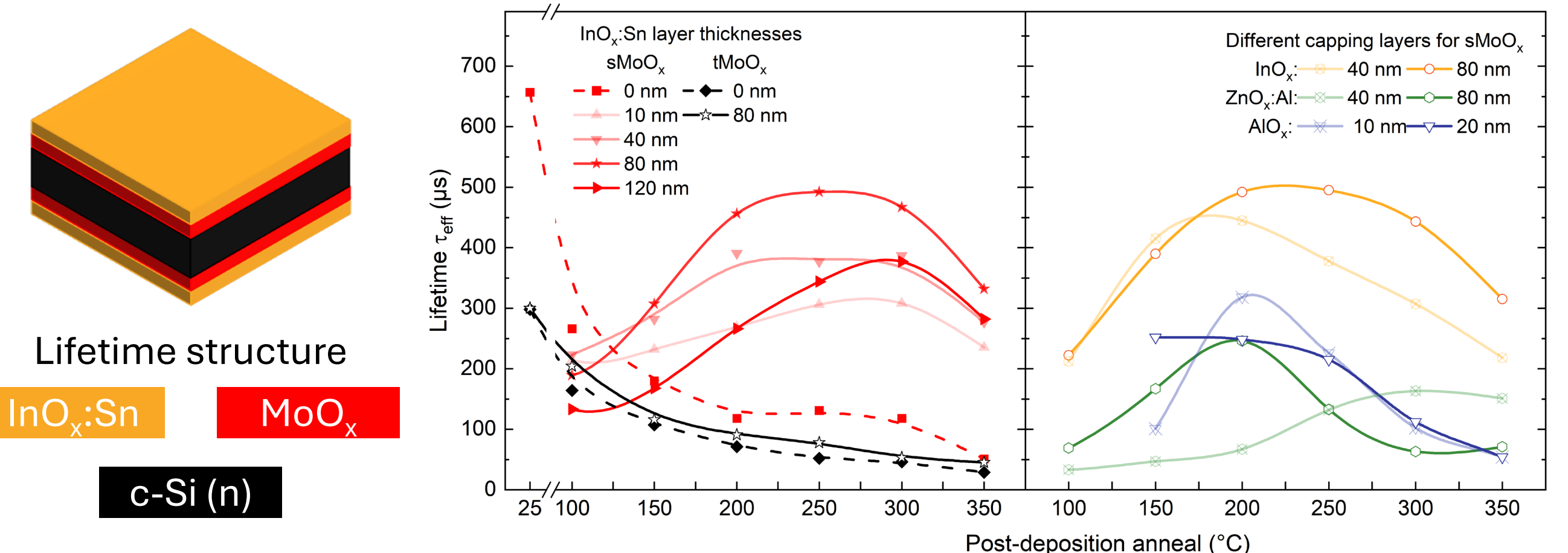
Passivation Performance

- Effective carrier lifetime (τ_{eff}) for sMoO_x reached up to 740 μs
- Passivation attributed to the formation of a thin SiO_x interlayer during chemical deposition.



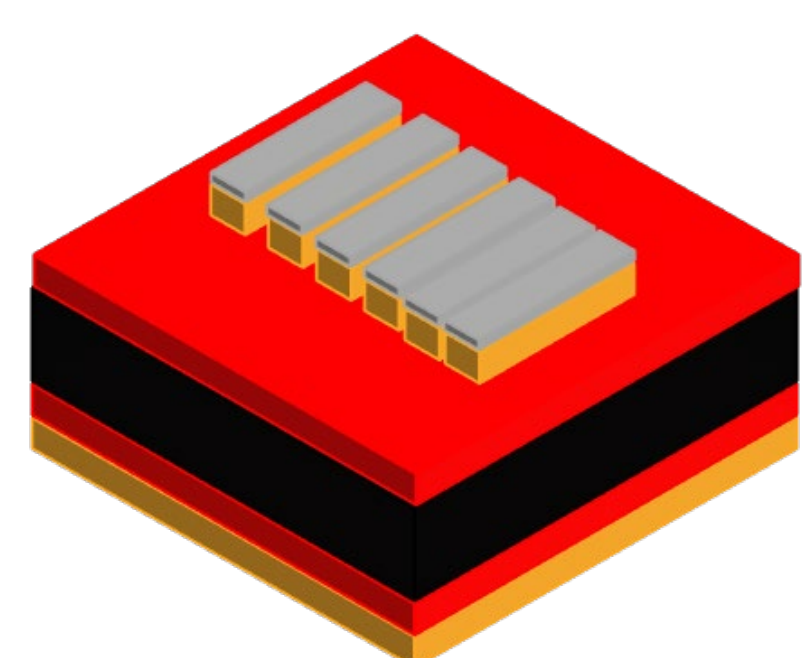
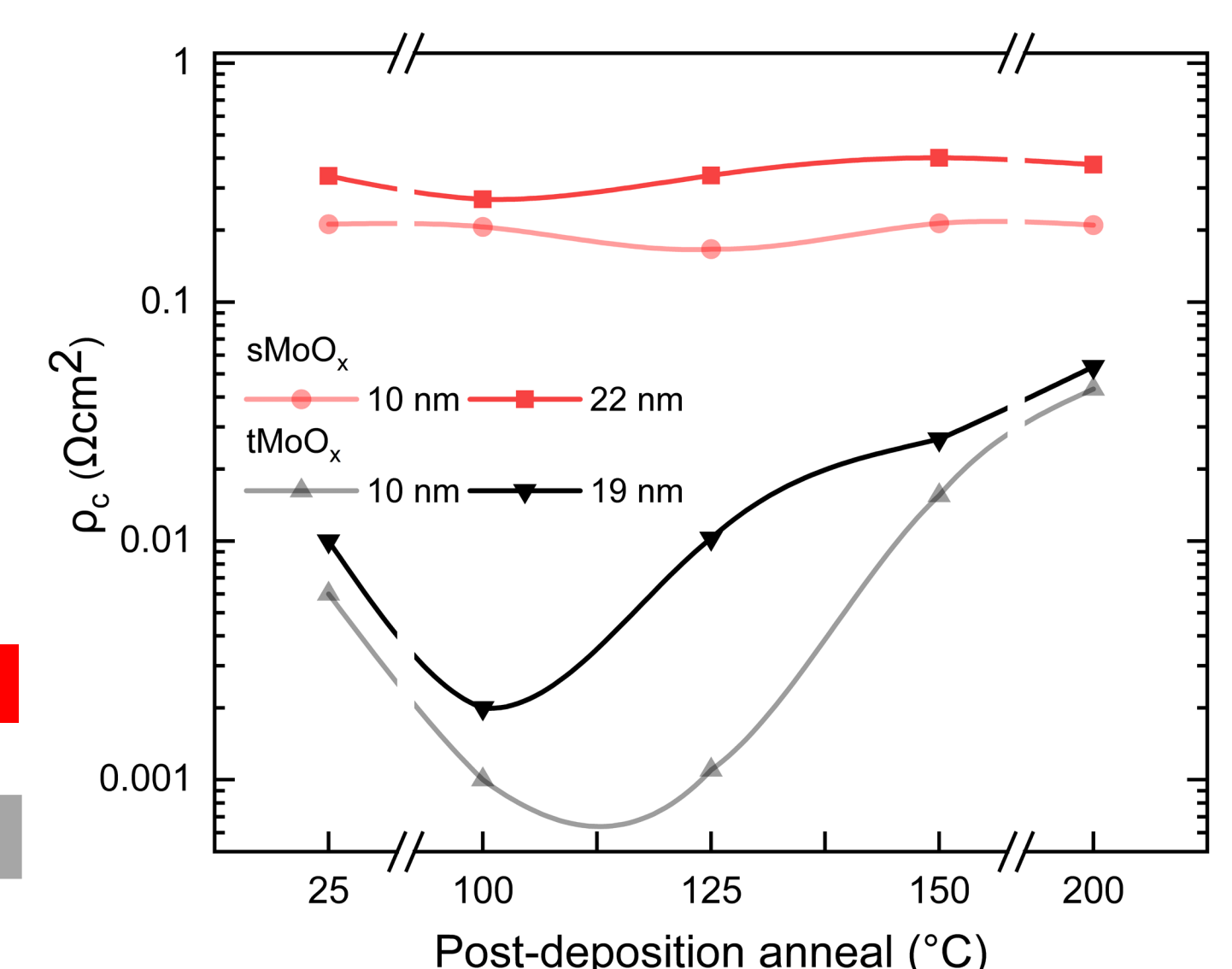
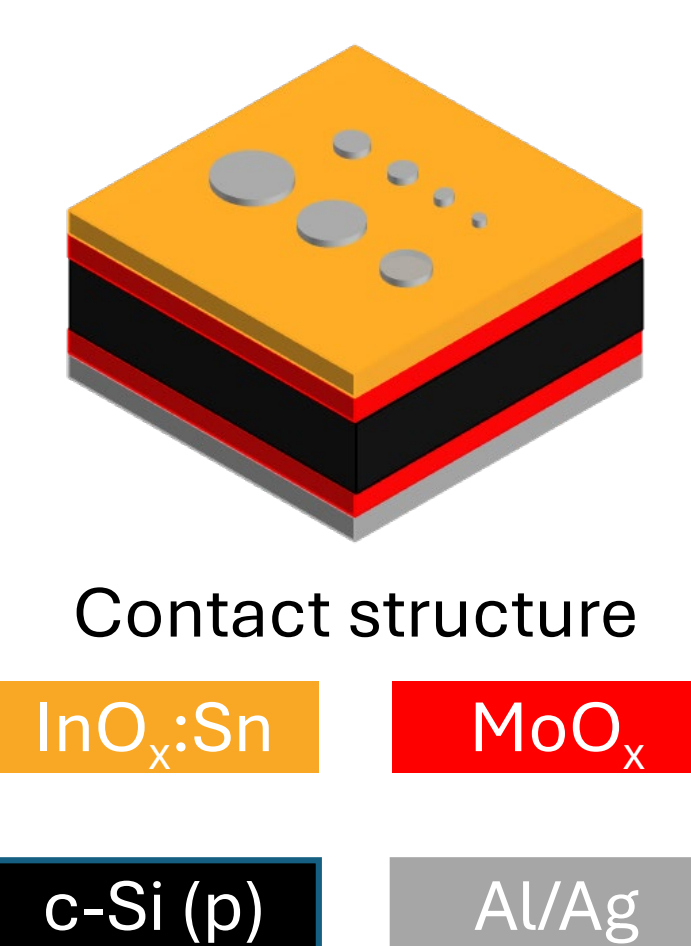
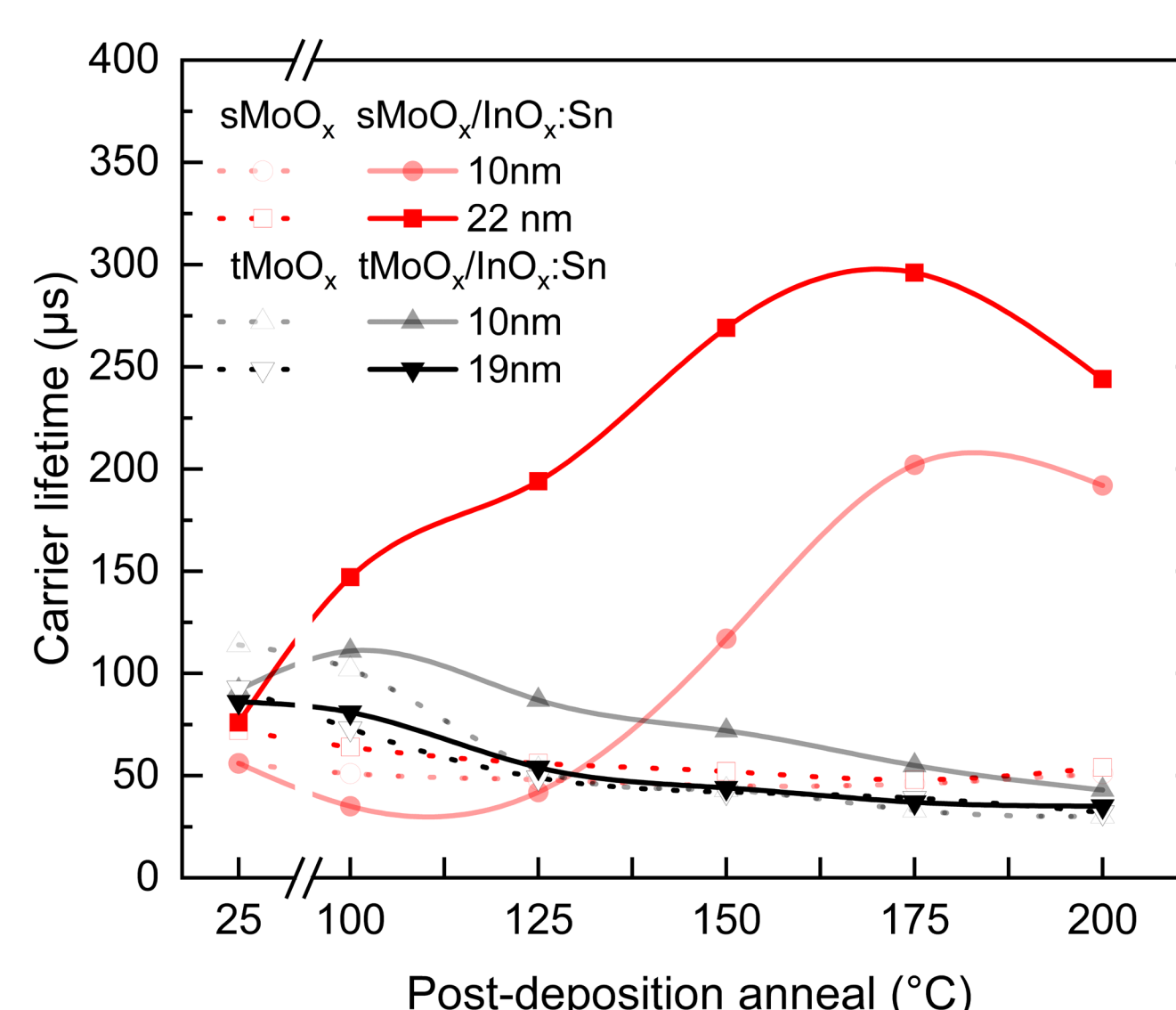
Capping Layer Effects

- ITO capping configuration achieved $\tau_{\text{eff}} \approx 500 \mu\text{s}$ around 250 °C and maintained $\tau_{\text{eff}} > 200 \mu\text{s}$ at 350 °C.
- This improvement is attributed to hydrogen retention at the c-Si/ SiO_x / sMoO_x interface during annealing.
- InO_x capping also achieved $\tau_{\text{eff}} \approx 500 \mu\text{s}$ after annealing up to 300 °C, comparable to ITO.

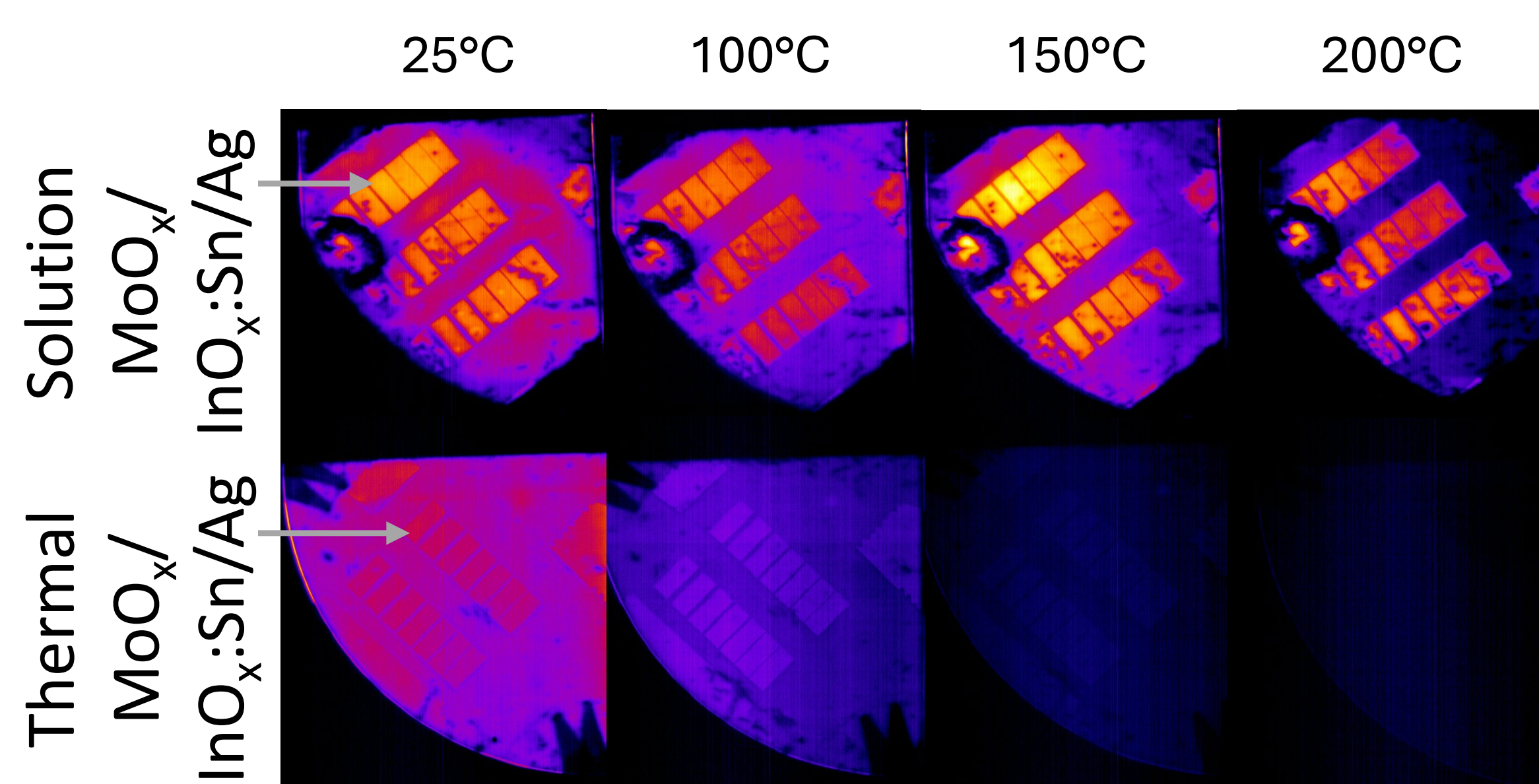
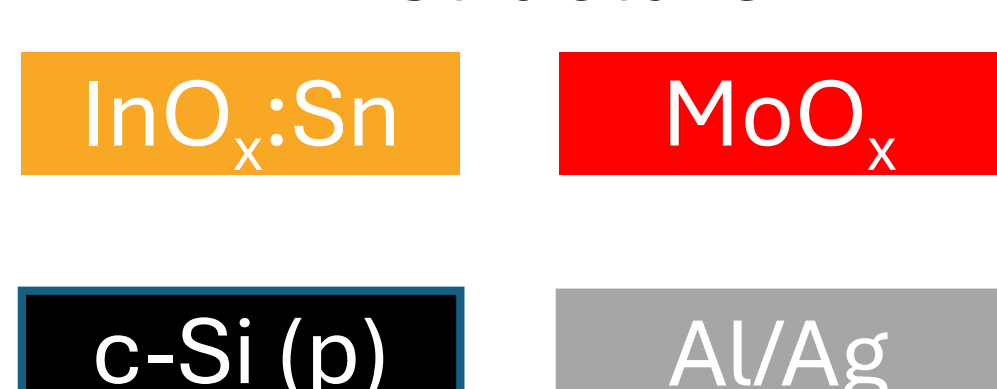


p-type Passivation and Contact Resistivity

- While initial passivation lifetime was lower on p-type c-Si ($\tau_{\text{eff}} = 50\text{--}150 \mu\text{s}$), annealing improved lifetimes for sMoO_x with ITO capping layers, reaching up to $\tau_{\text{eff}} = 300 \mu\text{s}$ for ~22 nm films.
- Although contact resistivity ρ_c values for sMoO_x ($\sim 0.3 \Omega\cdot\text{cm}^2$) is higher than tMoO_x , it remains suitable for full-area contacts.



PL structure



Post-Metallization Stability

sMoO_x /ITO stacks retained and even enhanced passivation after Ag metallization and annealing, unlike tMoO_x , which degraded rapidly above 100 °C.